PATENT
Atty. Dkt. No. APPM/2981/CPES/EPS/BG

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

5/17/02
#191
5/8/02
MW

In re Application of: Reimer, et al.

Serial No.: 09/220,153

Confirmation No.: 3858

Filed: December 23, 1998

For: Processing Apparatus Having Integrated Pumping System

Group Art Unit: 1763

Examiner: R. Bueker

Assistant Commissioner for Patents
Washington, D.C. 20231

CERTIFICATE OF MAILING
37 CFR 1.8
I hereby certify that this correspondence is being deposited on 7 May 02 with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.
7 May 02 (Date) Cullen B Patten (Signature)

Dear Sir:

SUPPLEMENTAL RESPONSE TO OFFICE ACTION DATED AUGUST 30, 2001

This response is intended to supplement Applicant's Response to Office Action dated August 30, 2001, for which the shortened statutory time period for response was extended three-months to expire on February 28, 2002. The Commissioner is authorized to charge Deposit Account No. 20-0782/APPM/2981/CPES/EPS/WBP $84.00 for one additional claim, along with any other fees to make this response timely.

IN THE CLAIMS:

Please add the following new claims:

107. An apparatus for processing a substrate, the apparatus comprising:

(a) a chamber; and

(b) a high capacity pump adjacent to the chamber, the pump having an inlet connected to the chamber to rapidly evacuate gas in the chamber and an outlet that exhausts the evacuated gas to atmospheric pressure, the pump having an operating rotational speed of not more than 12,000 rpm.

New Matter
(Spec. says 10,000)

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